

Title (en)  
TEMPERATURE SENSOR AND METHOD FOR PRODUCTION THEREOF

Title (de)  
TEMPERATURSENSOR UND VERFAHREN ZU DESSEN HERSTELLUNG

Title (fr)  
CAPTEUR DE TEMPERATURE ET PROCEDE DE FABRICATION DUDIT CAPTEUR

Publication  
**EP 1516166 A1 20050323 (DE)**

Application  
**EP 03742855 A 20030213**

Priority  
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Abstract (en)  
[origin: WO03093778A1] A temperature sensor of durable construction is disclosed, which may be simply installed and packaged, is uncomplicated to produce and with which rapid changes in temperature may be reliably recorded. The temperature sensor (1) comprises a silicon substrate (2) in which at least one porous region (3) is embodied, whereby the degree of porosity and the thickness of the porous region (3) is selected such that the porous region (3) is thermally decoupled from the silicon substrate (2). The temperature sensor (1) further comprises temperature measuring elements (6, 7), for recording the temperature difference between the silicon substrate (2) and the porous region (3). The temperature sensor can furthermore comprise heating means for testing the sensor function.

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